

<b>Notice of References Cited</b>	Application/Control No.	Applicant(s)/Patent Under Reexamination	
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Examiner	Art Unit	2822	Page 1 of 1
Toniae M. Thomas			

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**NON-PATENT DOCUMENTS**

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.